

FORM: PTO-1449 (REV: 7-80)	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	Atty Docket No: 00-0737.00/US	Serial No: Not Assigned
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (37 CFR 1.98(b)) (use several sheets if necessary)		Applicant: David S. Pecora	
		Filing Date: Concurrently Herewith (May 11, 2001)	Group: Not Assigned

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	
	AA					
	AB					
	AC					
	AD					
	AE					
	AF					
	AG					
	AH					
	AI					
	AJ					
	AK					

11002 U.S. PTO
09/05/2006
05/11/01

FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation	
	AL					Yes	No
	AM						
	AN						
	AO						
	AP						
	AQ						

Initial

OTHER ART (including author, title, date, pertinent pages, etc.)

Bt	AR		"Highly Selective Etching of Silicon Nitride Over Silicon and Silicon Dioxide," J. Vac. Sci. Technol. A 17(6), Nov/Dec 1999
	AS		
	AT		
	AU		

Examiner: Binh Tran	Date Considered: 10/21/03
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication with applicant.